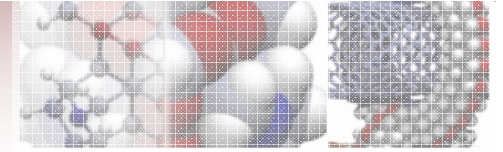


# ***Nanotexturarea periodica a suprafetelor metalice cu pulsuri laser ultrascurte***

***Catalina Radu<sup>1\*</sup>, Adrian Dinescu<sup>2</sup>, Marian Zamfirescu<sup>1,2</sup>***

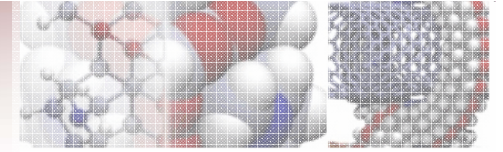
- 1) INFLPR – Bucuresti, Atomistilor 409, 077125 Magurele, Romania.***
- 2) IMT – Bucuresti, Str. Erou Iancu Nicolae 126A, 077190 Bucuresti, Romania .***

***\* Email: catalina.radu@inflpr.ro, Tel: +4 021 457 5066***



# ***Sumarul prezentarii***

- *Scopul principal urmarit*
- *Procesarea laser a filmelor subtiri metalice: Ti, Ni, Cr, Pt*
- *Experimente de procesare in diferite conditii de expunere laser*
- *Concluzii*

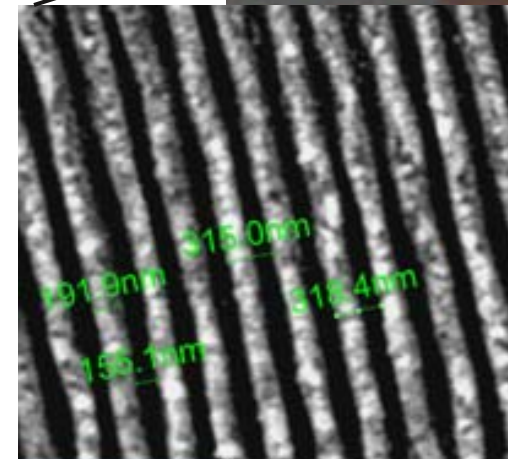


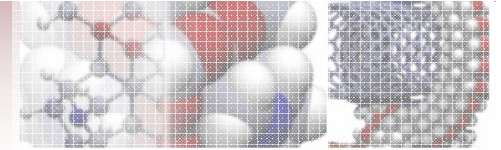
## *Scopul principal urmarit*

- Dezvoltarea unor metode optice de procesare a materialelor la nivel nanometric pe suprafete extinse.

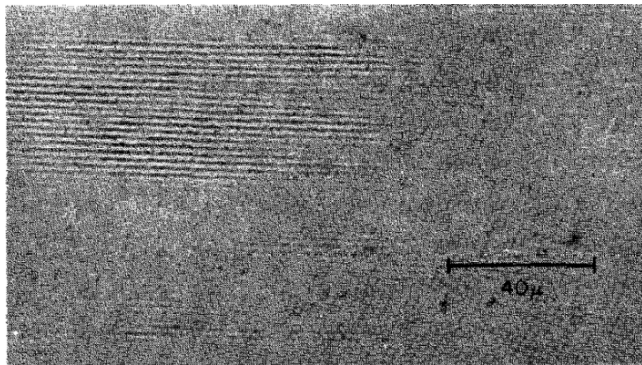
### **Aplicatii:**

- Marcaje de securitate.
- Modificarea proprietatilor tribologice ale suprafetei materialelor.
- Marirea suprafetei efective pentru cresterea sensibilitatii micro-senzorilor.





## ***1965 - Primele evidente ale formarii structurilor periodice***



**Semiconductor Surface Damage Produced  
by Ruby Lasers\***

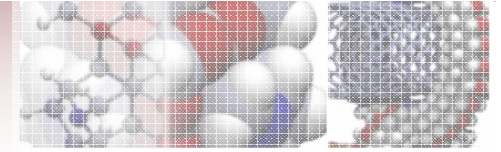
MILTON BIRNBAUM

*Aerospace Corporation, El Segundo, California*

(Received 21 January 1965; in final form 24 June 1965)

### ***Teorii existente asupra formarii structurilor periodice***

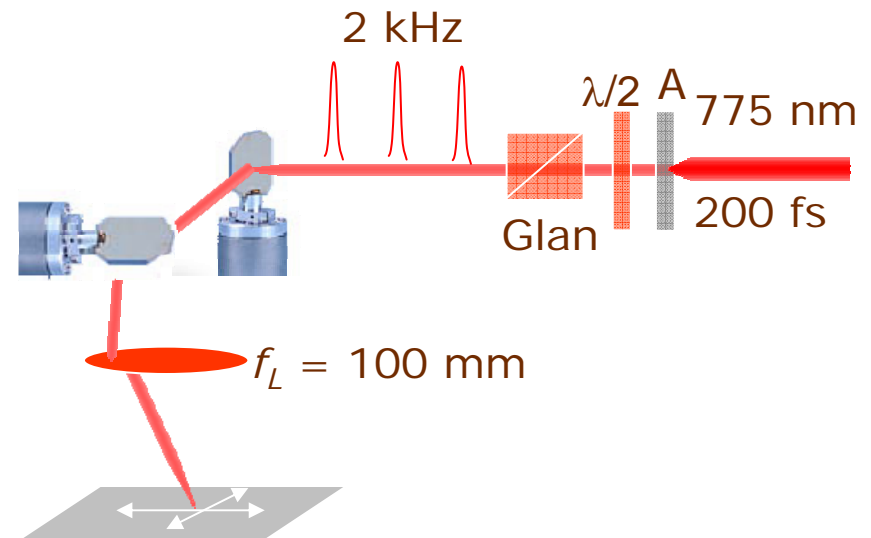
- a) Teoria interferentiala (ablatie laser) – Sipe et al. 1983***
- b) Teoria autorganizarii (topire si recristalizare) – J. Reif et al. 2002***
- c) Teoria plasmei de electroni (ablatie laser) – Y. Shimotsuma et al. 2003***
- d) Teoria plasmonilor de suprafata (ablatie laser) – J. Miyaji et al. 2008***



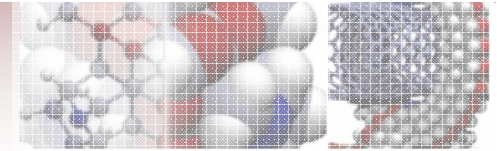
# Procesarea laser a suprafetelor

## Condițiile de procesare laser:

- **Laser cu pulsuri ultrascurte: 200 fs, lungime de unda 775 nm, frecvența de repetiție 2 kHz.**
- **Dimesiune spot laser 35  $\mu\text{m}$ .**
- **Fluente laser sub pragul de ablatie.**
- **Scanarea suprafeței:**
  - a) **translatarea probei (XY).**
  - b) **scanare cu oglinzi galvanometrice**
    - permite procesare pe arii mari
    - in timp scurt (mm/s).



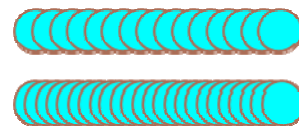
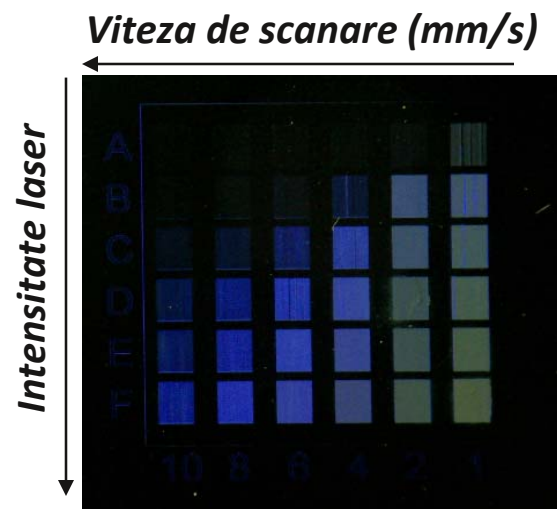
**Metoda de “scriere” directă**



# Experimente de procesare in diferite conditii de expunere laser

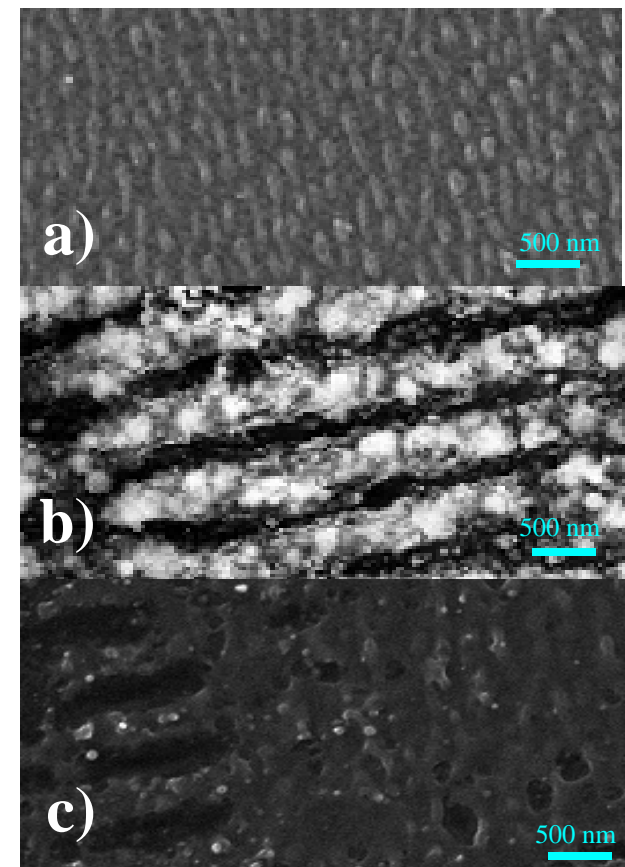
Morfologia structurilor depinde de:

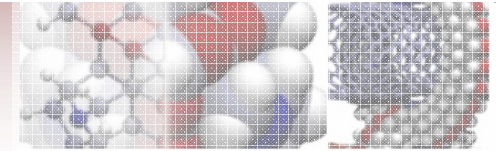
- *fluanta laser* : 0.09 - 0.3 J/cm<sup>2</sup>
- *numar pulsuri (viteza de scanare)* : 1-10 mm/s
- *polarizare*
- *natura materialului*



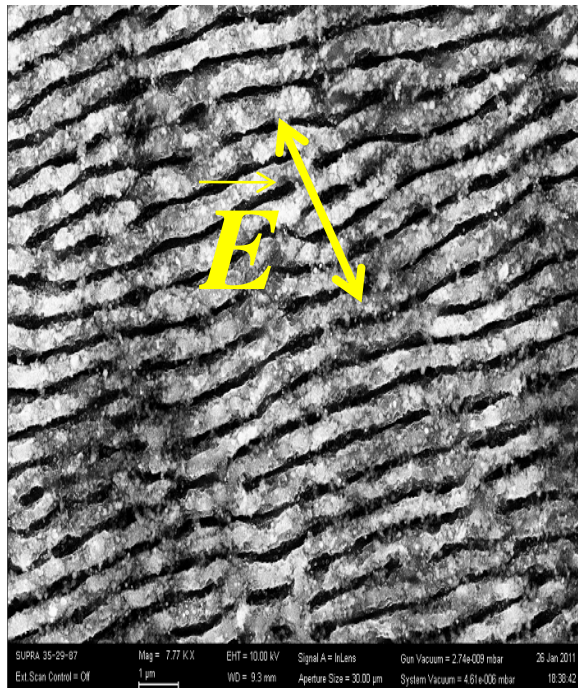
Film Ni 150 nm / Si (111)

- a) A1: 1 mm/s, 0.18 J/cm<sup>2</sup>
- b) D2 : 2 mm/s, 0.23 J/cm<sup>2</sup>
- c) F1 : 1 mm/s, 0.25 J/cm<sup>2</sup>

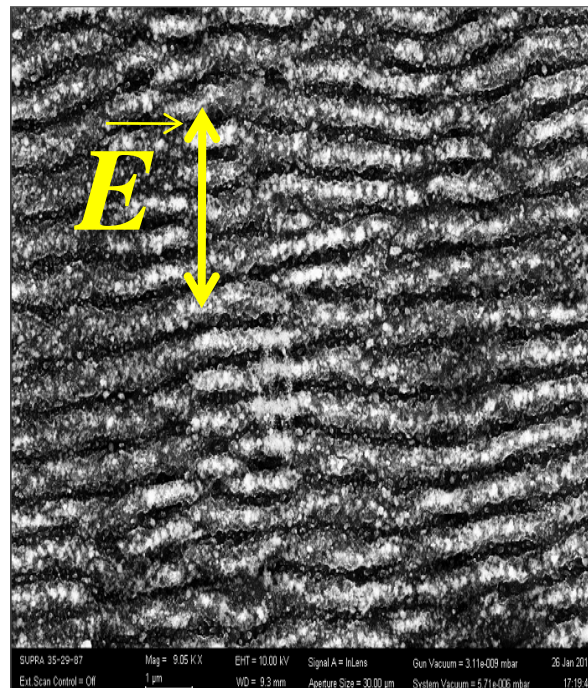




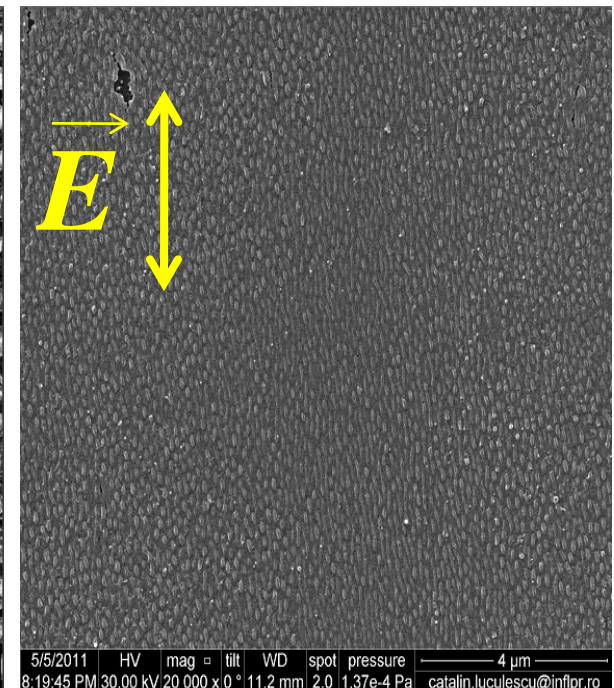
# *Dependenta orientarii structurilor periodice de directia de polarizare a laserului*



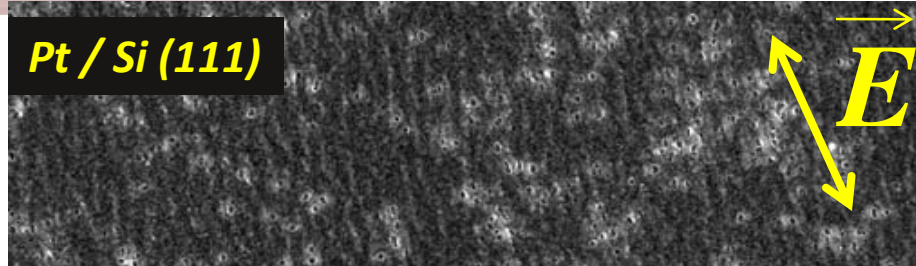
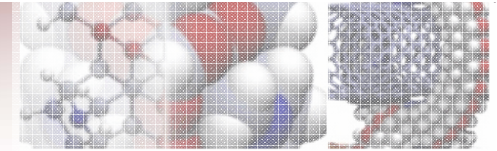
Ni



Ti



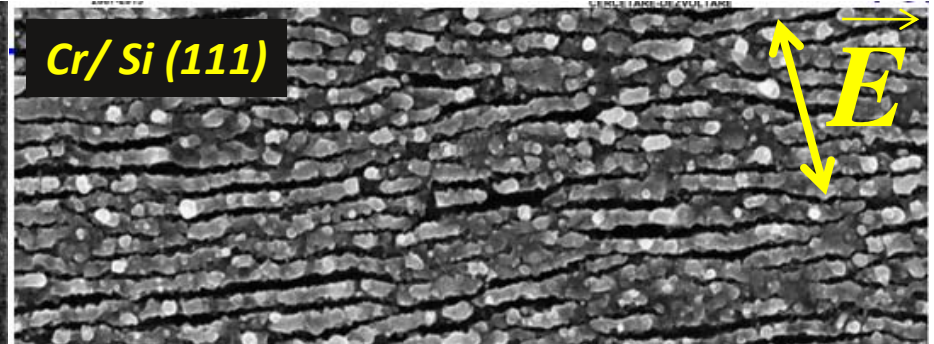
Ni



**Pt / Si (111)**

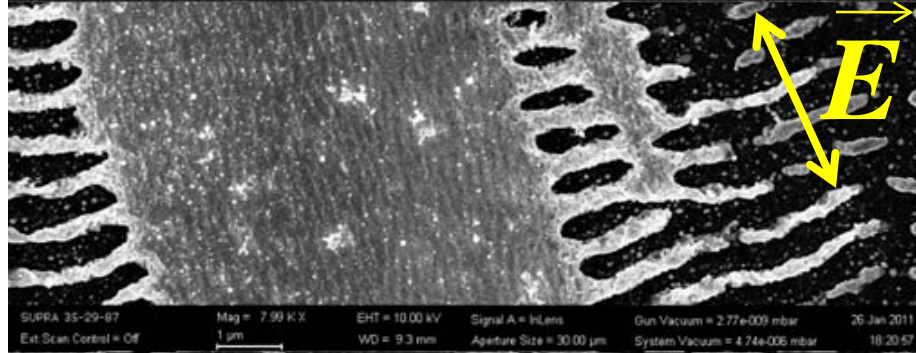
**Frecventa spatiala inalta (HSFL)**

SUPRA 35-29-87 Mag = 12.28 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.78e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 1 μm WD = 9.3 mm Aperture Size = 30.00 μm System Vacuum = 4.63e-005 mbar 18:29:36

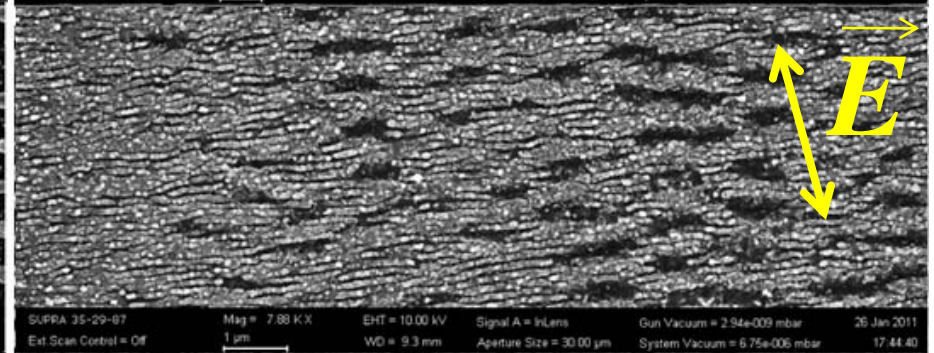


**Cr/ Si (111)**

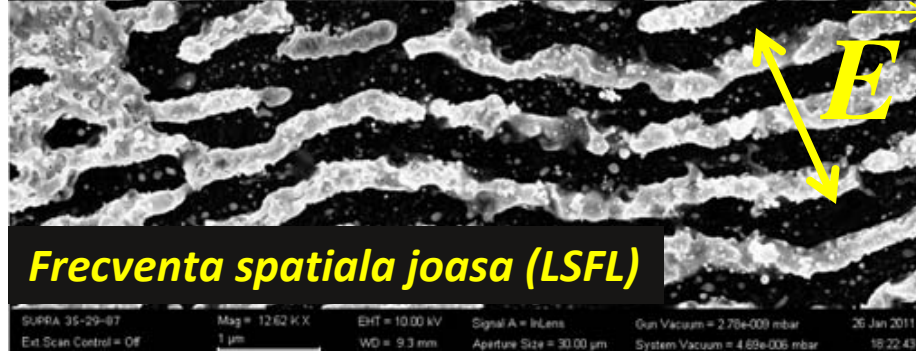
SUPRA 35-29-87 Mag = 25.59 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.94e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 200 nm WD = 9.3 mm Aperture Size = 30.00 μm System Vacuum = 5.30e-005 mbar 17:36:59



SUPRA 35-29-87 Mag = 7.99 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.77e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 1 μm WD = 9.3 mm Aperture Size = 30.00 μm System Vacuum = 4.74e-005 mbar 18:20:57

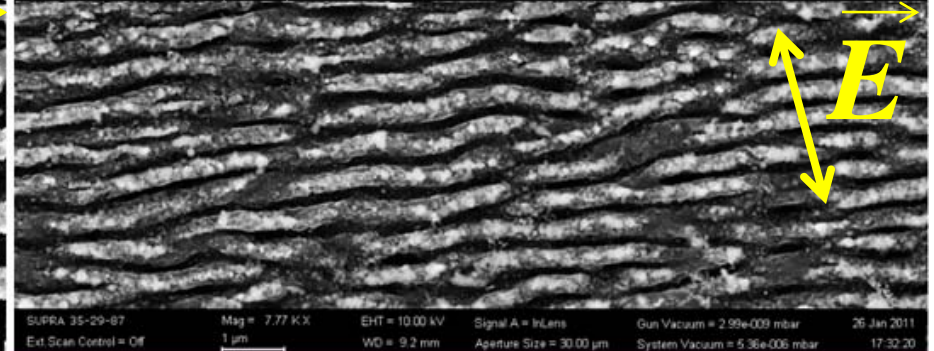


SUPRA 35-29-87 Mag = 7.88 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.94e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 1 μm WD = 9.3 mm Aperture Size = 30.00 μm System Vacuum = 6.75e-005 mbar 17:44:40



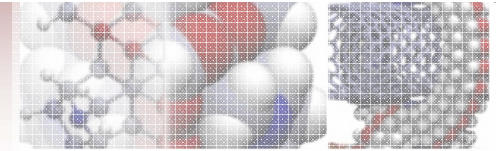
**Frecventa spatiala joasa (LSFL)**

SUPRA 35-29-87 Mag = 12.62 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.78e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 1 μm WD = 9.3 mm Aperture Size = 30.00 μm System Vacuum = 4.69e-005 mbar 18:22:43

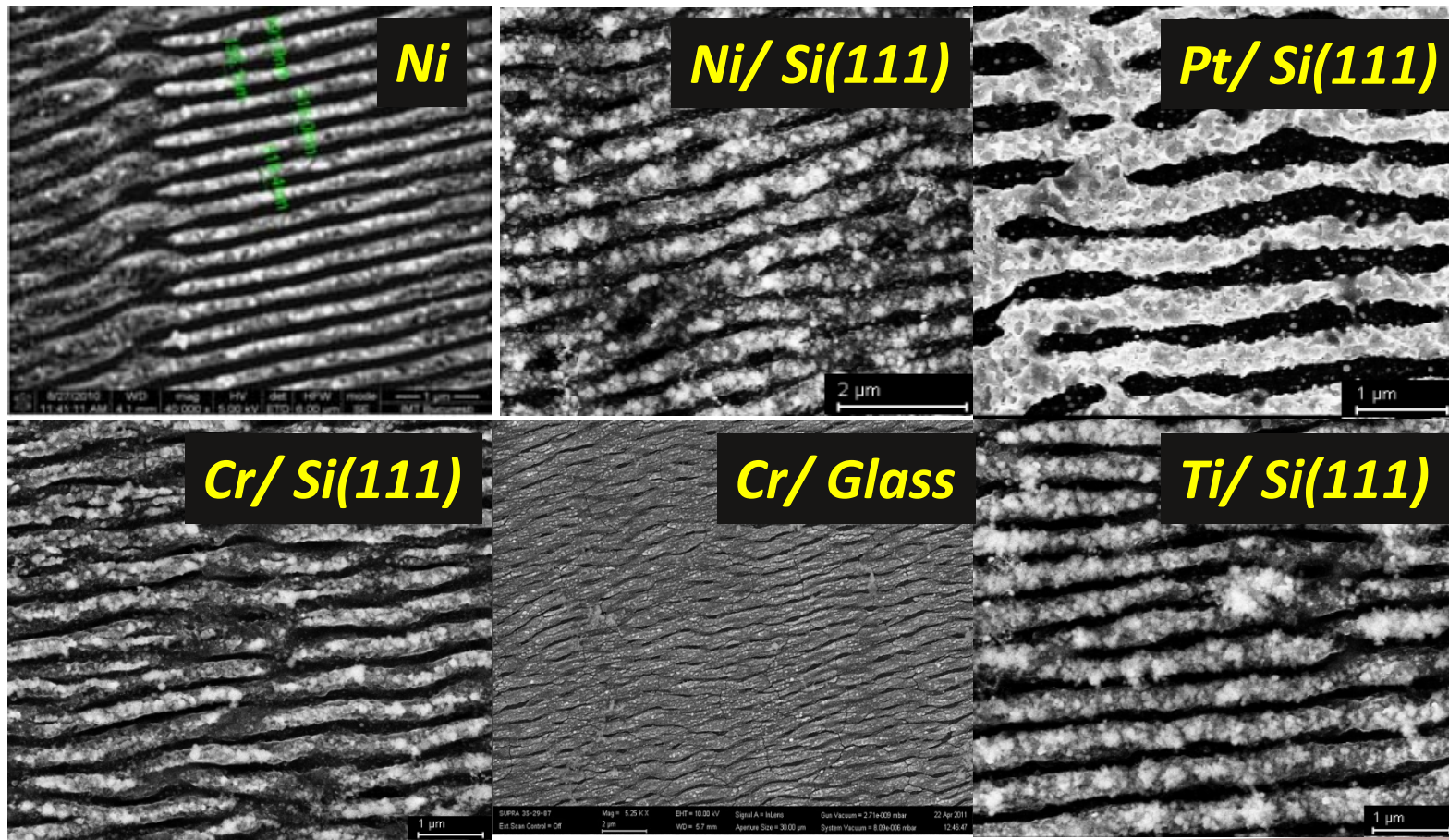


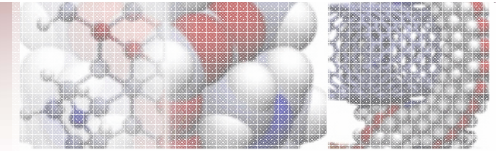
SUPRA 35-29-87 Mag = 7.77 K X EHT = 10.00 kV Signal A = InLens Gun Vacuum = 2.99e-009 mbar 26 Jan 2011  
Ext. Scan Control = Off 1 μm WD = 9.2 mm Aperture Size = 30.00 μm System Vacuum = 5.36e-005 mbar 17:32:20



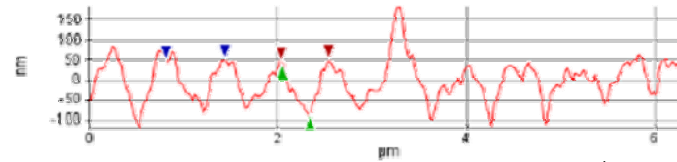
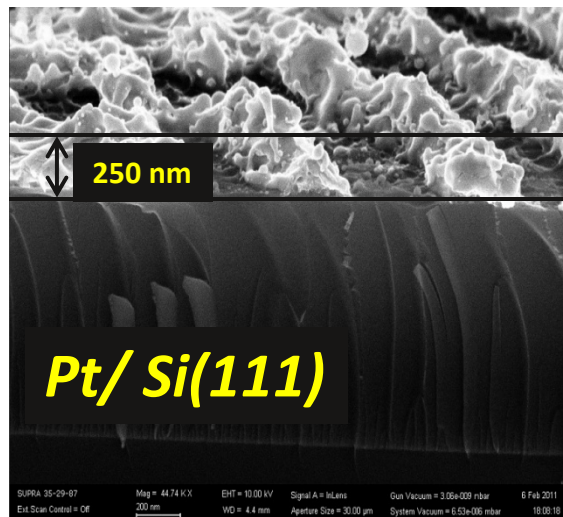


# *Dependenta morfologiei structurilor periodice de natura materialului*





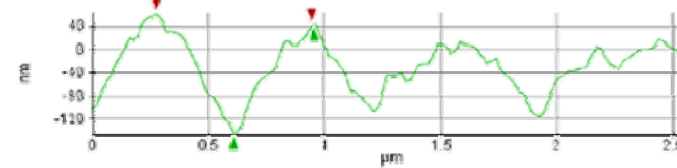
# Caracterizare SEM si AFM



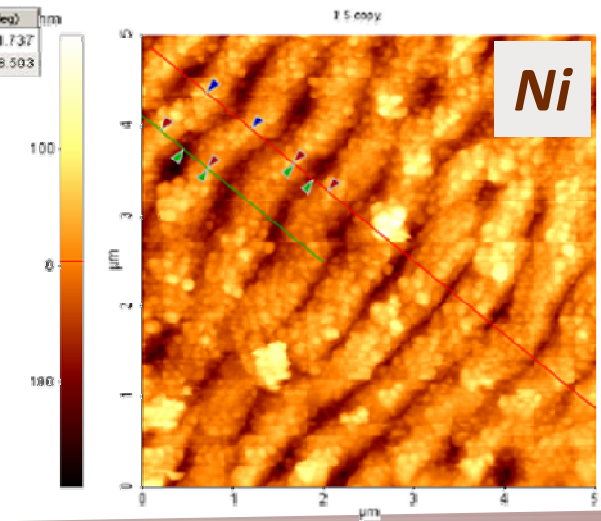
Cursor	$\Delta X(\mu\text{m})$	$\Delta Y(\text{nm})$	Angle(deg)
Red	0.493	3.135	0.390
Green	0.282	-124.929	-23.928
Blue	0.627	1.452	0.133

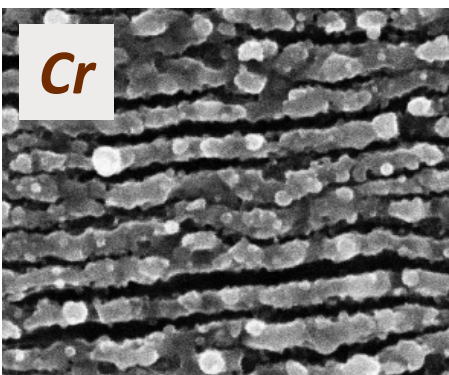
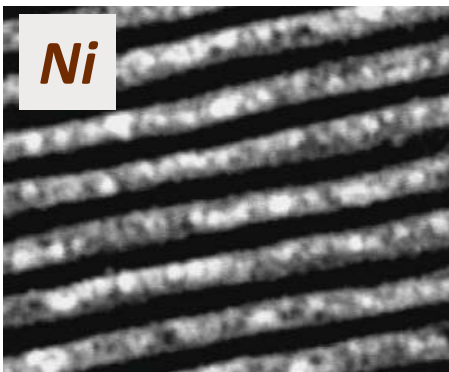
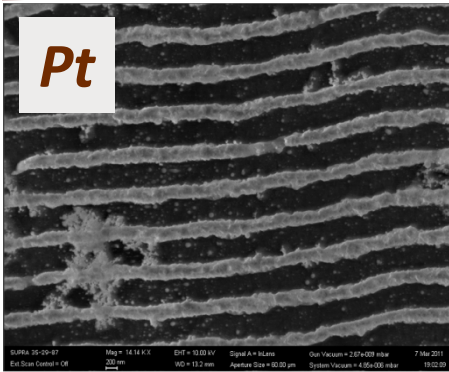
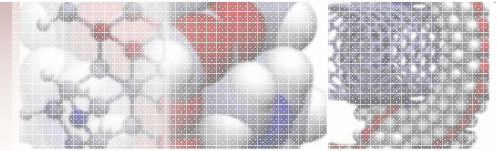
$\Lambda = 500\text{-}600 \text{ nm}$   
 $h = 190 \text{ nm}$

Line Profile: Green



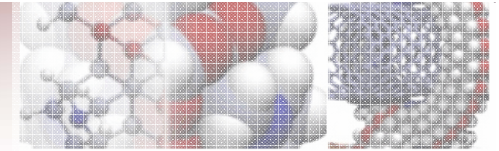
Cursor	$\Delta X(\mu\text{m})$	$\Delta Y(\text{nm})$	Angle(deg)
Red	0.671	-20.331	-1.737
Green	0.348	189.114	28.503





# Dependenta perioadei structurilor de natura materialului

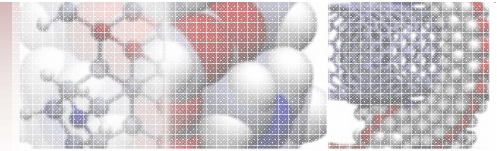
Material	Perioada structurilor $\Lambda$	Indice de refractie @ $\lambda = 775$ nm	$\lambda_0/n$
Ni	HSFL: 160-190 nm	2,43-i*4,31	318 nm
	HSFL: 300-330 nm $\perp$		
	LSFL: 600-660 nm $\perp$		
Ti	HSFL: 90-120 nm	2,74-i*3,3	282 nm
	LSFL: 460-530 nm $\perp$		
Pt	HSFL: 190-220 nm	2,76-i*4,84	280 nm
	LSFL: 550- 600 nm $\perp$		
Cr	HSFL : 120-140 nm $\perp$	3,11-i*3,44	249 nm
	LSFL: 630-690 nm $\perp$		



## *Concluzii*

- S-au obtinut suprafete nano-structurate cu laserul femtosecunde pe suprafete metalice pe arie extinsa ( $\text{mm}^2$ ).
- Perioada structurilor auto-organizate depinde de natura materialului si conditiile de iradiere (100-700 nm).
- Orientarea structurilor periodice depinde de directia de polarizare a radiatiei laser. Nu depinde de directia de scanare.





***Va multumesc pentru atentie!***

M.Zamfirescu multumeste Proiectului POSDRU/89/1.5/S/63700  
pentru suportul financiar.



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